

INFORMATION DISCLOSURE STATEMENT

Applicant : Paraschiv, et al.
App. No : 10/797,888
Filed : March 9, 2004
For : METHOD FOR SELECTIVE
REMOVAL OF HIGH-K MATERIAL
Examiner : Vinh, Lan
Art Unit : 1765

CERTIFICATE OF MAILING

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on

February 21, 2006

(Date)

Rose M. Thiessen, Reg. No. 40,202

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application is a PTO/SB/08 Equivalent listing 7 references to be considered by the Examiner. Also enclosed are 4 foreign patent references and/or non-patent literature as listed on the Information Disclosure Statement.

This Information Disclosure Statement is being filed before the mailing date of a final action and before the mailing of a Notice of Allowance. This Statement is accompanied by the fees set forth in 37 C.F.R. § 1.17(p). The Commissioner is hereby authorized to charge any additional fees which may be required or to credit any overpayment to Account No. 11-1410.

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Dated: 2/21/06

Respectfully submitted,

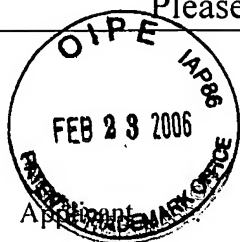
KNOBBE, MARTENS, OLSON & BEAR, LLP

By: [Signature]

Rose M. Thiessen
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Please Direct All Correspondence to Customer Number **20995**



TRANSMITTAL LETTER
INFORMATION DISCLOSURE STATEMENT

Applicant: Paraschiv, et al.

App. No : 10/797,888

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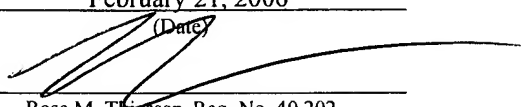
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Rose M. Thiessen, Reg. No. 40,202**Mail Stop Amendment**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Dear Sir:

Enclosed for filing in the above-identified application are:

- (X) An Information Disclosure Statement and PTO/SB/08 equivalent listing references for consideration:
- (X) Listing 7 references.
 - (X) Enclosing 4 references.
- (X) Check in the amount of \$180.
- (X) The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment, to Account No. 11-1410.
- (X) Return prepaid postcard.



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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Application No.	10/797,888
	Filing Date	March 9, 2004
	First Named Inventor	Paraschiv, Vasil
	Art Unit	1765
(Multiple sheets used when necessary)	Examiner	Vinh, Lan
SHEET 1 OF 1	Attorney Docket No.	IMEC312.001AUS

U.S. PATENT DOCUMENTS

Examiner Initials	Cite No.	Document Number Number - Kind Code (if known) Example: 1,234,567 B1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear
	1	2003/109106 a1	06/12/2003	Pacheco Rotondaro Antonio Luis, et al.	
	2	5,271,797 a	12/21/1993	Kamisawa et al.	
	3	4,087,367	05/02/1978	Riout et al.	

FOREIGN PATENT DOCUMENTS

Examiner Initials	Cite No.	Foreign Patent Document Country Code-Number-Kind Code Example: JP 1234567 A1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear	T ¹
	4	EP 0 968 979 A	01/05/2000	Siemens Aktiengesellschaft		

NON PATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ¹
	5	WATANABE D, et al., <i>Selective Wet Etching for High-K Material by Organic Solvent Containing Hydrofluoric Acid</i> , Semiconductor Pur Water and Chemicals Conference, 02/17/2003, pp. 117-130, XP008057967.	
	6	CHRISTENSON, K. <i>Selective Wet Etching of High-K Materials</i> , Solid State Technology Online, 07/03/2003 pp. 1-7, XP002361400.	
	7	European Search Report for related European Application No. EP 04447059.9, mailed on February 8, 2006.	

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Examiner Signature	Date Considered
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

T¹ - Place a check mark in this area when an English language Translation is attached.